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Advanced Fabrication Technologies for Micro/Nano Optics and Photonics IX

**Georg von Freymann
Winston V. Schoenfeld
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Editors

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Contents

vii	<i>Authors</i>
ix	<i>Conference Committee</i>

ADVANCED FABRICATION METHODS FOR NANOPLASMONICS

9759 05	Two-dimensional silver nanodot array fabricated using nanoporous alumina for a chemical sensor platform of localized surface plasmon resonance [9759-4]
9759 06	Scalable structural color printing using pixelated nanostructures in RGB primary colors [9759-5]

ION-BEAM FABRICATION FOR NANOPHOTONICS

9759 08	Ultrafast third-harmonic spectroscopy of single nanoantennas fabricated using helium-ion beam lithography (Invited Paper) [9759-7]
9759 0A	Investigation and optimization of Rowland ghosts in high efficiency spectrometer gratings fabricated by e-beam lithography [9759-9]

LIGHT EXTRACTION AND GUIDING

9759 0C	Controlled guidance of light through a flexible optical waveguide sheet [9759-11]
9759 0D	Polymer strip-loaded waveguides on ALD-TiO₂ films [9759-12]
9759 0E	Fabrication of low-loss ridge waveguides in z-cut lithium niobate by combination of ion implantation and UV picosecond laser micromachining [9759-13]

3D PHOTONIC STRUCTURES

9759 0H	Holographic fabrication of 3D photonic crystal templates with 4, 5, and 6-fold rotational symmetry using a single beam and single exposure [9759-15]
---------	---

ADVANCED MANUFACTURING USING A DMD OR OTHER SLM: JOINT SESSION WITH CONFERENCES 9759 AND 9761

9759 0P	Size scaling with light patterned dielectrophoresis in an optoelectronic tweezers device [9759-23]
9759 0R	Fabrication of waveguide spatial light modulators via femtosecond laser micromachining [9759-25]
9759 0S	Assembling silver nanowires using optoelectronic tweezers [9759-26]

LARGE AREA FABRICATION

- 9759 0U **Fabrication of large area flexible PDMS waveguide sheets** [9759-28]
- 9759 0W **Tunable Fabry-Pérot interferometer with subwavelength grating reflectors for MWIR microspectrometers** [9759-30]

3D LASER STRUCTURING DEVICES AND LITHOGRAPHY I: JOINT SESSION WITH CONFERENCES 9738 AND 9759

- 9759 0Y **Photonics walking up a human hair (Invited Paper)** [9759-32]
- 9759 10 **Study of 3D printing method for GRIN micro-optics devices** [9759-34]
- 9759 11 **Beam-bending in spatially variant photonic crystals at telecommunications wavelengths** [9759-35]

3D LASER STRUCTURING DEVICES AND LITHOGRAPHY II: JOINT SESSION WITH CONFERENCES 9738 AND 9759

- 9759 16 **Multi-photon lithography of 3D micro-structures in As_2S_3 and $\text{Ge}_5(\text{As}_2\text{Se}_3)_9\text{s}$ chalcogenide glasses** [9759-41]

3D LASER STRUCTURING DEVICES AND LITHOGRAPHY III: JOINT SESSION WITH CONFERENCES 9738 AND 9759

- 9759 17 **Fabrication of metasurface-based infrared absorber structures using direct laser write lithography** [9759-42]

POSTER SESSION

- 9759 1A **Novel fabrication technique of hybrid structure lens array for 3D images** [9759-46]
- 9759 1B **Slanted liquid microlens array by using diffuser** [9759-47]
- 9759 1C **Nanoimprint of large-area optical gratings on a conventional photoresist using a teflon-coated nanoimprint mold** [9759-48]
- 9759 1D **Fabrication of liquid-filled square lens array with hemispherical partition walls** [9759-49]
- 9759 1E **WGP structures patterned by Lloyd's mirror laser interference lithography system integrate into MEMS physical sensor device** [9759-50]
- 9759 1F **Lens array fabrication method with volume expansion property of PDMS** [9759-51]
- 9759 1G **Fabrication of plasmonic crystals using programmable nanoreplica molding process** [9759-52]

- 9759 1H **Rate controlled metal assisted chemical etching to fabricate vertical and uniform Si nanowires** [9759-53]
- 9759 1I **Surface-enhanced Raman spectroscopy substrate fabricated via nanomasking technique for biological sensor applications** [9759-55]
- 9759 1M **Design and fabrication of local fill fraction in photonic crystal templates using a spatial light modulator** [9759-60]

Authors

Numbers in the index correspond to the last two digits of the six-digit citation identifier (CID) article numbering system used in Proceedings of SPIE. The first four digits reflect the volume number. Base 36 numbering is employed for the last two digits and indicates the order of articles within the volume. Numbers start with 00, 01, 02, 03, 04, 05, 06, 07, 08, 09, 0A, 0B...0Z, followed by 10-1Z, 20-2Z, etc.

Ahmadi, Leila, 0D	Kautschor, L.-O., 08
Badshah, Mohsin A., 1G	Kim, Cheoljoong, 1A, 1B, 1D
Banasch, Michael, 0A	Kim, Junoh, 1A, 1B, 1D, 1F
Bang, Yousung, 1F	Kim, Seok-min, 1G
Barker, Jayk E., 16	Kim, T.-R., 05
Batista, Daniel, 11	Knopf, George K., 0C, 0U
Bauman, Stephen J., 11	Kollmann, H., 08
Becker, S. F., 08	Kontturi, Ville, 0D
Beyer, A., 08	Koo, Gyohyun, 1A, 1B, 1D
Bordatchev, Evgueni, 0C, 0U	Kuebler, Stephen M., 11, 16
Böscher, G., 08	Kuittinen, Markku, 0D
Bove, V. Michael, 0R	Kurth, Steffen, 0W
Buresi, Matteo, 0Y	Labh, Shreya, 16
Cheng, Y. C., 10	Laukkanen, Janne, 0D
Choi, Y.-W., 05	Lee, Jooho, 1F
Chuang, Tzu-Han, 1E	Lee, Junsik, 1A, 1B, 1D
Cooper, Jonathan M., 0S	Lee, Muyoung, 1F
Darweesh, Ahmad A., 11	Lee, S., 05
Datta, Bianca, 0R	Lee, W., 10
Digaum, Jennefir L., 11	L'hullier, J. A., 0E
Ebermann, Martin, 0W	Lienau, C., 08
Esmann, M., 08	Lin, Te-Hsun, 1E
Fanyaeu, Ihar, 17	Lin, Yuankun, 0H, 1M
Flügel-Paul, Thomas, 0A	Liu, Longju, 1G
Fu, Chien-Chung, 1E	Lokhande, Vaibhav, 1H
Fuentes, Angel, 0P	Lowell, David, 0H, 1M
George, David, 0H, 1M	Lu, Meng, 1G
Gessner, Thomas, 0W	Lutkenhaus, Jeffrey, 0H, 1M
Gleason, Benn, 16	Lyu, Y., 1C
Gölzhäuser, A., 08	Martella, Daniele, 0Y
Green, Robert, 0U	Mayer, Theresa S., 16
Herrmann, T., 0E	Meinig, Marco, 0W
Herzog, Joseph B., 11	Mizeikis, Vygantas, 17
Heusinger, Martin, 0A	Neale, Steven L., 0P, 0S
Hiller, Karla, 0W	Neumann, Norbert, 0W
Hong, Shuo-Ting, 1E	Nicholson-Smith, Chloë, 0C
Honkanen, Seppo, 0D	Park, N., 08
Hsu, W. Y., 10	Parmeggiani, Camilla, 0Y
Huynh, C., 08	Pazos, Javier J., 11
Jang, WonJae, 1F	Philipose, Usha, 0H
Ji, M.-G., 05	Piao, X., 08
Ji, Taeksoo, 1H	Pogrebnyakov, Alexej, 16
Jiang, Hao, 06	Ramos-Garcia, Ruben, 0P
Jolly, Sundeep, 0R	Richardson, Gerald D., 16
Jugessur, A. S., 1C	Richardson, Kathleen A., 16
Jung, M., 05	Rivero-Baleine, Clara, 16
Juvert, Joan, 0P	Rodriguez Luna, Juan Carlos, 0P
Kaminska, Bozena, 06	Roussey, Matthieu, 0D
Karydis, Thrasyvoulos, 0R	Rumpf, Raymond C., 11

Saarinen, Jyrki, 0D
Sapia, Ryan J., 16
Savidis, Nickolaos, 0R
Schwarz, Casey M., 16
Seifert, Mario, 0W
Sharma, Rashi, 11
Shin, Dooseub, 1A, 1B, 1D
Silies, M., 08
Song, Ari, 1H
Stolze, M., 0E
Tseng, Kuo-Chun, 1E
Vieker, H., 08
Wang, P. J., 10
Wasyliczyk, Piotr, 0Y
Wecker, Julia, 0W
Wiersma, Diederik S., 0Y
Won, Yong Hyub, 1A, 1B, 1D, 1F
Woo, D., 05
Wu, C. Y., 10
Wu, N. H., 10
Yeh, J. A., 10
Yun, Seokhun, 1H
Zeitner, Uwe D., 0A
Zeng, Hao, 0Y
Zhang, A., 1C
Zhang, Hualiang, 0H, 1M
Zhang, Shuailong, 0S

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- 1 Advanced Fabrication Methods for Nanoplasmonics
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Sandra Wolff, Technische Universität Kaiserslautern (Germany)
- 3 Light Extraction and Guiding
Stefan Linden, Rheinische Friedrich-Wilhelms- Universität Bonn (Germany)
- 4 3D Photonic Structures
Saulius Juodkazis, Swinburne University of Technology (Australia)
- 5 Novel Approaches for Sensing
Miguel Anaya, Consejo Superior de Investigaciones Científicas (Spain)
- 6 Advanced Manufacturing using a DMD or other SLM: Joint Session with Conferences 9759 and 9761
Philip S. King, Texas Instruments Inc. (United States)
Georg von Freymann, Technische Universität Kaiserslautern (Germany)
- 7 Large Area Fabrication
Ruth Houbertz, Multiphoton Optics GmbH (Germany)
- 8 3D Laser Structuring Devices and Lithography I: Joint Session with Conferences 9738 and 9759
Stephen M. Kuebler, CREOL, The College of Optics and Photonics, University of Central Florida (United States)
- 9 3D Laser Structuring Devices and Lithography II: Joint Session with Conferences 9738 and 9759
Georg von Freymann, Technische Universität Kaiserslautern (Germany)
- 10 3D Laser Structuring Devices and Lithography III: Joint Session with Conferences 9738 and 9759
Winston V. Schoenfeld, CREOL, The College of Optics and Photonics, University of Central Florida (United States)

- 11 3D Laser Structuring Devices and Lithography IV: Joint Session with
Conferences 9738 and 9759
Michael Thiel, Nanoscribe GmbH (Germany)

